

## APPLICATION DATA SHEET

Electronic Version v14

Stylesheet Version v14.0

<b>Title of Invention</b>	ELECTRON DIFFRACTION SYSTEM FOR USE IN PRODUCTION ENVIRONMENT AND FOR HIGH PRESSURE DEPOSITION TECHNOLOGY		
Application Type: regular, utility Attorney Docket Number: B1180/20019			
Correspondence address:  <b>Customer Number:</b> 03000 *03000*			
Priority Data:  Doc.No: EP 02020889.8; Country - EP; Date: 2002-09-18 us-priority-claimed			
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